

U.S. UTILITY Patent Application

<i>MR</i>	O.I.P.E.	PATENT DATE
SCANNED <i>7480</i>	O.A. <i>TM</i>	

APPLICATION NO. 09/848577	CONT/PRIOR F	CLASS 118	SUBCLASS 715	ART UNIT 1763	EXAMINER MUNCE H. H. H.
------------------------------	-----------------	--------------	-----------------	------------------	-------------------------------

TITLE: Reactor for depositing thin film on wafer
 APPLICANTS: Young-Hoon Park

PTO-2040
12/89

[illegible]

TERMINAL DISCLAIMER	DRAWINGS			CLAIMS ALLOWED	
<input type="checkbox"/> The term of this patent subsequent to _____ (date) has been disclaimed.	Sheets Drwg. _____	Figs Drwg. _____	Print Fig. _____	Total Claims _____	Print Claim for O.G. _____
<input checked="" type="checkbox"/> The term of this patent shall not extend beyond the expiration date of U.S Patent No. _____	<div style="display: flex; justify-content: space-between;"> (Assistant Examiner) (Date) </div> <div style="display: flex; justify-content: space-between;"> (Primary Examiner) (Date) </div> <div style="display: flex; justify-content: space-between;"> (Legal Instruments Examiner) (Date) </div>			NOTICE OF ALLOWANCE MAILED	
<input type="checkbox"/> The terminal _____ months of this patent have been disclaimed.				ISSUE FEE	
WARNING: The information disclosed herein may be restricted. Unauthorized disclosure may be prohibited by the United States Code Title 35, Sections 122, 181 and 368. Possession outside the U.S. Patent & Trademark Office is restricted to authorized employees and contractors only.				Amount Due _____	Date Paid _____
				ISSUE BATCH NUMBER	

Form PTO-438A
(Rev. 6/98)

FILED WITH: ☐ DISK (CRF) ☒ FICHE ☐ CD-ROM
(Attached in pocket on right inside flap)

BEST AVAILABLE COPY

(FACE)